



Article

Exceedingly High Performance Top-Gate P-Type SnO Thin Film Transistor with a Nanometer Scale Channel Layer

Te Jui Yen ¹, Albert Chin ^{1,*} and Vladimir Gritsenko ^{2,3,4}¹ Department of Electronics Engineering, National Chiao Tung University, Hsinchu 300, Taiwan² Rzhanov Institute of Semiconductor Physics, Siberian Branch, Russian Academy of Sciences, Novosibirsk, Russia³ Novosibirsk State University, Novosibirsk, Russia⁴ Novosibirsk State Technical University, Novosibirsk, Russia

* Correspondence: email: achin@nctu.edu.tw, Tel.: +886-3-5731841

Received: date; Accepted: date; Published: date

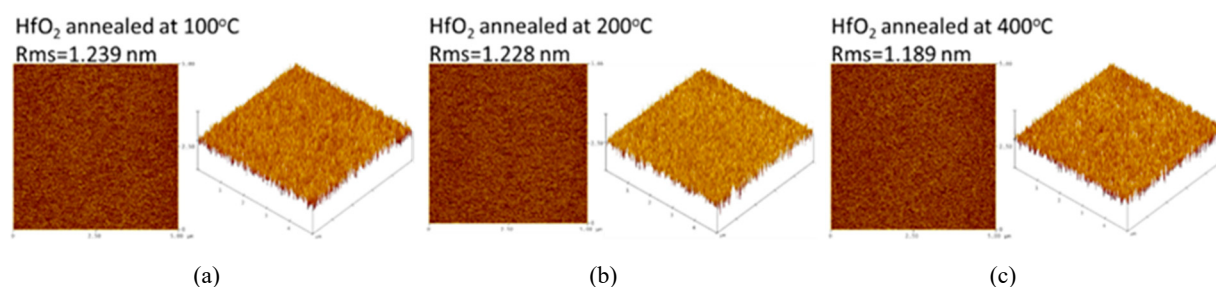


Figure S1. The surface roughness analysis of HfO₂ annealed at (a) 100 °C, (b) 200 °C and (c) 400 °C through AFM.

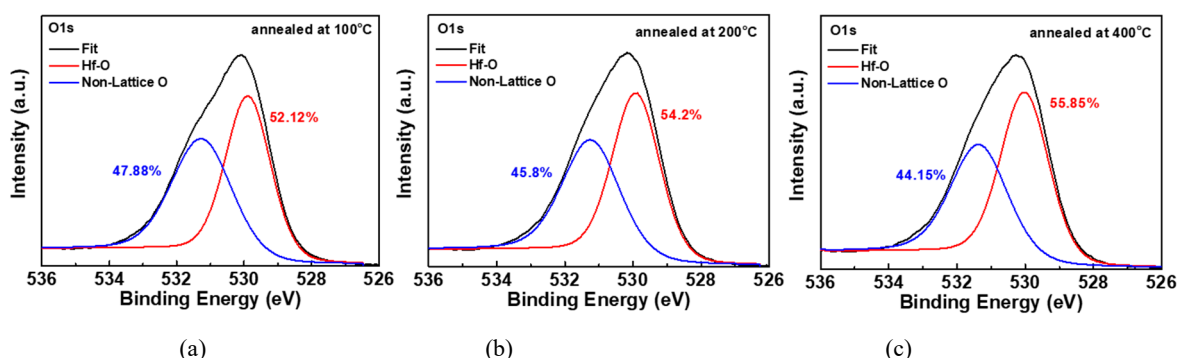


Figure S2. The O_{1s} spectra of HfO₂ films annealed at (a) 100°C, (b) 200°C and (c) 400°C.